

## PACKAGING & ASSEMBLY

### Chamber Oven

(High temperature sintering with temperature profiling)

Manufacturer: Nabertherm

Model: HTCT 03/16



### General Description:

The High Temperature Chamber Oven is designed for thermal processing of small to medium large samples up to 1600 °C. The chamber can achieve fast heating rates (up to 30 °C/min) and allows working under controllable atmosphere using an automatic gas-flow controller.

### Key Specifications:

- Maximal T: 1600 °C
- Heating elements: SiC
- Chamber dimensions: 120 x 210 x 120 mm
- Maximal heating range: 30 °C/min
- Controlled atmosphere: automatic gassing system; calibration for N<sub>2</sub>
- Digital PID-temperature control

<b>Availability</b>	Use allowed for all researchers with permission
<b>Location</b>	Environmental Lab Europastraße 12 9524 Villach
<b>Responsibles / Contact</b>	Dr. Jochen Bardong Tel.:+43 4242 56300 209